















For high throughput and highly efficient temperature management



THE EMT-MK has an integrated controller and a temperature management system. Reduce of material's outgassing with a compact size. Multiple interface options are available. Air or water cooling as requested.

BENEFITS

- Ultra-high vacuum
- Integrated controller
- Installation in any orientation
- Safety standards
- Most energy efficient temperature management
- Water cooled (air cooling only on request)





Models	EMT1700MK	EMT2200MK	ЕМТЗЗООМК	EMT3800MK	EMT4200MK
Pumping speed in I/s	1,650	2,200	3,300	3,600	4,200
Ultimate pressure Pa	< 2,00E-7	< 2,00E-7	< 2,00E-7	< 5,00E-7	< 5,00E-7
Backing pump (recommended) I/min			> 2,000		
Inlet flange diameter DN	DN200	DN250	DN320	DN320	DN350
Throughput N2 (sccm)	4400	4400	2100	2800	2800
Start up time (min)	< 10	< 10	< 11	< 12	< 12
Stop time (min)	< 10	< 10	< 11	< 12	< 12
Height in mm	501.5	446.5	445	501	444
Size in mm (diameter)	Ø340	Ø340	Ø380	Ø415	Ø415
Weight in kg (Standard)	65	62	70	80	75

APPLICATIONS FOR EMT-MK

EUV lithography (extreme ultra violet)

Micro-machining (MEMS)

CD line width measurement

SEM/TEM Electron

Microscopy

XPS

Nano technology

Ion plating

Sputtering

For further information, technical data or drawings please contact ⊠ components@ebara-pm.eu

EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced technology.

EBARA supports



EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs approximately 150 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and an overhaul centre for vacuum pumps.



